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## (54) FORMING METHOD OF SKIN MATERIAL

## (57) Abstract:

PURPOSE: To transfer uneven embossed pattern to a sheet in good reproducibility by vacuum-forming a skin sheet with a female mold according to normal process and then heating it in the state of vacuum attraction.

CONSTITUTION: When uneven embossed pattern and complicated uneven shape of skin material are transferred onto the surface of an automobile instrument panel pad etc. the skin sheet is vacuum-formed with a

female mold having engraved embossed pattern on the mold surface, according to the normal process, then, the sheet is heated on the back of the skin at a temperature near the melting point in the state of vacuum attraction.

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